

L Number	Hits	Search Text	DB	Time stamp
-	2	4527059.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 15:46
-	2	4988879.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 13:47
-	2	5326633.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 13:48
-	8507	((surface substrate) with (("not" near porous) non-porous)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:53
-	1004	((surface substrate) with (("not" near porous) non-porous)) and (rough roughness)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:56
-	1560	((surface substrate) with (("not" near porous) non-porous)) and (adsor\$5 desor\$5 ioniz\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:57
-	1009	((surface substrate) with (("not" near porous) non-porous)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 15:50
-	65	((((surface substrate) with (("not" near porous) non-porous)) and (rough roughness)) and (((surface substrate) with (("not" near porous) non-porous)) and (adsor\$5 desor\$5 ioniz\$4)) and (((surface substrate) with (("not" near porous) non-porous)) and laser)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:30
-	15	((((surface substrate) with (("not" near porous) non-porous)) and (rough roughness)) and (((surface substrate) with (("not" near porous) non-porous)) and (adsor\$5 desor\$5 ioniz\$4)) and (((surface substrate) with (("not" near porous) non-porous)) and laser)) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:19
-	2	6399177.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:14
-	1	Sunner-Jan\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:19
-	1	Alimpiev-Sergey\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:20
-	1	Nikiforovl-Sergey\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:20
-	2	(((((surface substrate) with (("not" near porous) non-porous)) and (rough roughness)) and (((surface substrate) with (("not" near porous) non-porous)) and (adsor\$5 desor\$5 ioniz\$4)) and (((surface substrate) with (("not" near porous) non-porous)) and laser)) and (250/423R,424,425,423P.ccls.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 17:09
-	9	(((((surface substrate) with (("not" near porous) non-porous)) and (rough roughness)) and (((surface substrate) with (("not" near porous) non-porous)) and (adsor\$5 desor\$5 ioniz\$4)) and (((surface substrate) with (("not" near porous) non-porous)) and laser)) and (laser with puls\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:25

-	2	(((surface substrate) with ("not" near porous) non-porous)) and (((surface substrate) with ("not" near porous) non-porous)) and (rough roughness)) and (((surface substrate) with ("not" near porous) non-porous)) and laser)) and (250/423R,424,425,423P.ccls.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 16:30
-	187	(surface near rough\$4) same (non-porous ("not" adj porous))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 17:23
-	30	((surface near rough\$4) same (non-porous ("not" adj porous))) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 19:01
-	2	(((surface near rough\$4) same (non-porous ("not" adj porous))) and laser) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 17:24
-	45	((surface near rough\$4) same (non-porous ("not" adj porous))) and (nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:57
-	12	(((surface near rough\$4) same (non-porous ("not" adj porous))) and laser) and (nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 17:44
-	138	(non-porous ("not" adj porous)) with (rough roughness)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:56
-	27	((non-porous ("not" adj porous)) with (rough roughness)) and (adsor\$5 desor\$5 ioniz\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 09:59
-	16	(((non-porous ("not" adj porous)) with (rough roughness)) and (adsor\$5 desor\$5 ioniz\$4)) and (nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 19:01
-	1	(((non-porous ("not" adj porous)) with (rough roughness)) and (adsor\$5 desor\$5 ioniz\$4)) and (nanometer nm)) and (mass adj spectromet\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:59
-	2	(((non-porous ("not" adj porous)) with (rough roughness)) and (adsor\$5 desor\$5 ioniz\$4)) and (mass adj spectromet\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:59
-	2	((non-porous ("not" adj porous)) with (rough roughness)) and (mass adj spectromet\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 18:59
-	6	(((non-porous ("not" adj porous)) with (rough roughness)) and (adsor\$5 desor\$5 ioniz\$4)) and (nanometer nm)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/26 19:03
-	1943	laser same analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 09:59
-	34	(laser same analyte) and ((surface substrate) with ("not" near porous) non-porous))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:28

-	13	((laser same analyte) and ((surface substrate) with (("not" near porous non-porous))) and rough\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:11
-	9	((laser same analyte) and ((surface substrate) with (("not" near porous non-porous))) and rough\$4) and (nanometer nm nano-rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:02
-	0	20020187312.URPN.	USPAT	2004/02/27 10:59
-	13	((laser same analyte) and ((surface substrate) with (("not" near porous non-porous))) and rough\$4) and Laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:07
-	9	((laser same analyte) and ((surface substrate) with (("not" near porous non-porous))) and rough\$4) and (nanometer nm nano-rough\$4)) and Laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:12
-	8507	((surface substrate) with (("not" near porous non-porous))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:11
-	98	((surface substrate) with (("not" near porous non-porous))) and (rough\$4 with (nanometer nm nano- nano))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:22
-	42	((surface substrate) with (("not" near porous non-porous))) and (rough\$4 with (nanometer nm nano- nano)) and Laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:27
-	15	((surface substrate) with (("not" near porous non-porous))) and (rough\$4 with (nanometer nm nano- nano)) and Laser) and (adsor\$5 desor\$5 ioniz\$5 analyte)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:18
-	3	((surface substrate) with (("not" near porous non-porous))) and (rough\$4 with (nanometer nm nano- nano)) and Laser) and (laser with (desor\$5 ioniz\$5 analyte))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:21
-	23253	(gas\$4 analyte) with (rough\$4 nano-rough\$4 nano- nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:28
-	241	((gas\$4 analyte) with (rough\$4 nano-rough\$4 nano- nanometer nm)) and ((surface substrate) with (("not" near porous non-porous))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:25
-	130	((gas\$4 analyte) with (rough\$4 nano-rough\$4 nano- nanometer nm)) and ((surface substrate) with (("not" near porous non-porous))) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29
-	0	((gas\$4 analyte) with (rough\$4 nano-rough\$4 nano- nanometer nm)) and ((surface substrate) with (("not" near porous non-porous))) and laser) and (250/423R,424,425,423P.ccls.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:25
-	3	((gas\$4 analyte) with (rough\$4 nano-rough\$4 nano- nanometer nm)) and ((surface substrate) with (("not" near porous non-porous))) and laser) and (250/\$.ccls.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29
-	3	((surface substrate) with (("not" near porous non-porous))) and (rough\$4 with (nanometer nm nano- nano)) and Laser) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29

-	43545	metal with (rough\$4 nano-rough\$4 nano- nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29
-	663	(metal with (rough\$4 nano-rough\$4 nano- nanometer nm)) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29
-	397	((metal with (rough\$4 nano-rough\$4 nano- nanometer nm)) and analyte) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 11:29
-	28	((((metal with (rough\$4 nano-rough\$4 nano- nanometer nm)) and analyte) and laser) and (250/\$.ccls.))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:29
-	21287	metal with rough\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:48
-	1113	(metal with rough\$4) and ((nanometer nano nm) same rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:53
-	890	(metal with rough\$4) and (laser with (in situ))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:53
-	155	((metal with rough\$4) and ((nanometer nano nm) same rough\$4)) and ((metal with rough\$4) and (laser with (in situ)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:39
-	27	((((metal with rough\$4) and ((nanometer nano nm) same rough\$4)) and ((metal with rough\$4) and (laser with (in situ)))) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:48
-	198	(rough\$4 nano-rough\$4) with (("not" near porous) non-porous)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:02
-	22	((rough\$4 nano-rough\$4) with (("not" near porous) non-porous)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:55
-	3	((rough\$4 nano-rough\$4) with (("not" near porous) non-porous)) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:53
-	2	((((rough\$4 nano-rough\$4) with (("not" near porous) non-porous)) and laser) and (((rough\$4 nano-rough\$4) with (("not" near porous) non-porous)) and analyte)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:54
-	21287	(rough\$4 nano-rough\$4) with (metal)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:55
-	2654	((rough\$4 nano-rough\$4) with (metal)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:03

-	133	((rough\$4 nano-rough\$4) with (metal)) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:55
-	109	((((rough\$4 nano-rough\$4) with (metal)) and laser) and (((rough\$4 nano-rough\$4) with (metal)) and analyte)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 13:55
-	10	(((((rough\$4 nano-rough\$4) with (metal)) and laser) and (((rough\$4 nano-rough\$4) with (metal)) and analyte)) and 250/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:01
-	14	(mass near spectromet\$2) same ((rough\$4 nano-rough\$4 nano) with ("not" near porous) non-porous metal))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:13
-	10	((mass near spectromet\$2) same ((rough\$4 nano-rough\$4 nano) with ("not" near porous) non-porous metal))) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:03
-	10	((((mass near spectromet\$2) same ((rough\$4 nano-rough\$4 nano) with ("not" near porous) non-porous metal))) and laser) and ((nanometer nano nm))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:46
-	8200	((nanometer nano nm) with rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:49
-	2712	((nanometer nano nm) with rough\$4)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:53
-	221	((nanometer nano nm) with rough\$4)) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:13
-	137	(((((nanometer nano nm) with rough\$4)) and laser) and (((nanometer nano nm) with rough\$4)) and analyte)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:13
-	23	(((((nanometer nano nm) with rough\$4)) and laser) and (((nanometer nano nm) with rough\$4)) and analyte)) and ((mass near spectromet\$2) (ion adj mobility))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:13
-	16	(metal with rough\$4) same laser same analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:49
-	15	((metal with rough\$4) same laser same analyte) and (nanometer nano nm nano-)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:52
-	0	nano-rough\$4 with analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:52
-	150	rough\$4 with analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:53

-	77	(rough\$4 with analyte) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 14:53
-	57	((rough\$4 with analyte) and laser) and (nanometer nano nano- nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 15:03
-	5	((improv\$4 increas\$4) near3 analyte) with (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:41
-	0	20020187312.URPN.	USPAT	2004/02/27 15:52
-	39	Fonash-Stephen\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 15:53
-	6	Fonash-Stephen\$.in. and (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 15:53
-	93	((improv\$4 increas\$4) near3 ion) with (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 15:55
-	26	((improv\$4 increas\$4) near3 ion) with (rough\$4)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:23
-	359	((mass adj spectromet\$2) (ion adj mobility)) same rough\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:24
-	135	((mass adj spectromet\$2) (ion adj mobility)) same rough\$4) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:03
-	54	((mass adj spectromet\$2) (ion adj mobility)) same rough\$4) and laser) and analyte	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:23
-	3406	(ion analyte) with (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:23
-	705	((ion analyte) with (rough\$4)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:42
-	281	((ion analyte) with (rough\$4)) and ((mass adj spectromet\$2) (ion adj mobility))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:24
-	97	((ion analyte) with (rough\$4)) and laser) and ((ion analyte) with (rough\$4)) and ((mass adj spectromet\$2) (ion adj mobility)) )	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:24
-	59	((ion analyte) with (rough\$4)) and laser) and ((ion analyte) with (rough\$4)) and ((mass adj spectromet\$2) (ion adj mobility)) ) and (nanometer nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:25

-	51	(((ion analyte) with (rough\$4)) and laser) and (((ion analyte) with (rough\$4)) and ((mass adj spectromet\$2) (ion adj mobility)) ) and (nanometer nm)) and (silicon carbon polymer graphite)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:32
-	1	((enhanc\$4) near3 analyte) with (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:40
-	6	((enhanc\$4) near3 ion) with (rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:41
-	32	((analyte) with (rough\$4)) same (nanometer nm nano nano-)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:42
-	26	(((analyte) with (rough\$4)) same (nanometer nm nano nano-)) and laser	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:43
-	3	((absorb with analyte) same rough\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/02/27 16:49